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Instrumental Developments for In-situ Breakdown Experiments inside a Scanning Electron Microscope

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Abstract: Electrical discharges in accelerating structures are one of the key issues limiting the performance of future high energy accelerators such as the Compact Linear Collider (CLIC). Fundamental understanding of breakdown phenomena is an indispensable part of the CLIC feasibility study. The present work concerns the experimental study of breakdown using Scanning Electron Microscopes (SEMs). A SEM gives us the opportunity to achieve high electrical gradients of $1\text{ kV}/\mu\text{m}$ which corresponds to $1\text{ GV}/\text{m}$ by exciting a probe needle with a high voltage power supply and controlling the positioning of the needle with a linear piezo motor. The gap between the needle tip and the surface is controlled with sub-micron precision. A second electron microscope equipped with a Focused Ion Beam (FIB) is used to create surface corrugations and to sharpen the probe needle to a tip radius of about 50 nm . Moreover it is used to prepare cross sections of a voltage breakdown area in order to study the geometrical surface damages as well as the elemental composition of the breakdown.

Instrumental Developments for In-situ Breakdown Experiments inside a Scanning Electron Microscope

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Abstract

Electrical discharges in accelerating structures are one of the key issues limiting the performance of future high energy accelerators such as the Compact Linear Collider (CLIC). Fundamental understanding of breakdown phenomena is an important part of the CLIC feasibility study. The present work concerns the experimental study of breakdown using Scanning Electron Microscopes (SEMs). A SEM gives us the opportunity to achieve high electrical gradients of $1 \text{ kV}/\mu\text{m}$ which corresponds to $1 \text{ GV}/\text{m}$ by exciting a probe needle with a high voltage power supply and controlling the positioning of the needle with a linear piezo motor. The gap between the needle tip and the surface is controlled with sub-micron precision. A second electron microscope equipped with a Focused Ion Beam (FIB) is used to create surface corrugations and to sharpen the probe needle to a tip radius of about 50 nm . Moreover it is used to prepare cross sections of a voltage breakdown area in order to study the geometrical surface damages as well as the elemental composition of the breakdown.

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1 **1. Introduction**

2 The feasibility of future high power accelerators for particle physics stud-
3 ies such as the Compact Linear Collider (CLIC) are under investigation. The
4 high accelerating field of 100 MV/m is generated by sending radio-frequency
5 (rf) waves through specially designed accelerating structures. The high elec-
6 trical fields tend to cause surface degradation of accelerating structures [1].
7 The probability for an electrical breakdown will increase with the created
8 surface roughness which is critical to the performance of the accelerator.
9 One of the key conditions for the reliable operation of CLIC is limiting the
10 breakdown probability on the order of 10^{-7} . In order to obtain that con-
11 dition, studies of fatigue of the surface under rf condition with prototype
12 accelerating structures [2, 3] and direct current (dc) breakdown experiments
13 for example [4, 5, 6] are under way at CERN, SLAC and KEK. The dc
14 experiments have similarities in many aspects to high gradient rf tests but
15 are more easily equipped and controlled. However, existing dc experiments
16 use electrodes on the mm scale to give high gradient electric field on the
17 sample that is much larger than the surface roughness of the accelerating
18 structure. This macroscopic approach needs to be improved with respect to
19 the following issues

- 20 a) observed breakdowns and measured field emissions are averages in mm^2
21 areas;
- 22 b) the surface conditions of both electrode and sample surface are un-
23 known during experiments;

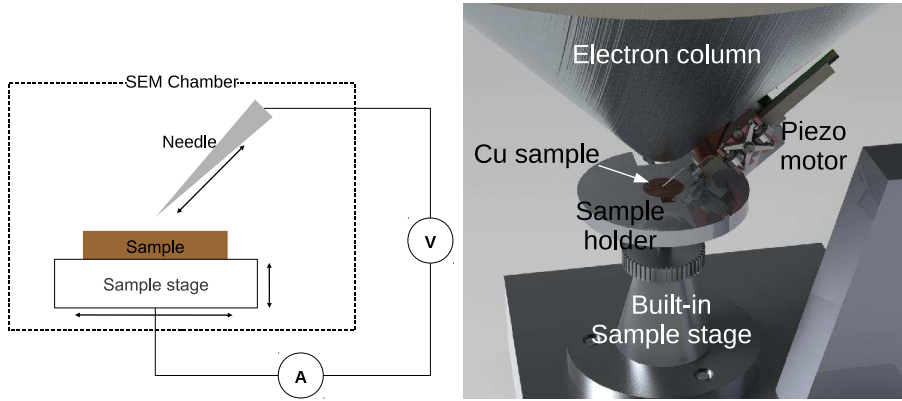


Figure 1: Schematic of experimental setup for field emission measurements and breakdown study (top), drawing of inside view of the ESEM chamber (bottom): both Cu sample and piezomotor are set on a same holder plate that is mounted on a built-in sample stage.

24 c) the gap between the electrode and the sample surface is not known to
 25 μm resolution.

26 The present work is intended to overcome these issues and provide an op-
 27 portunity to investigate localized breakdown phenomena by conducting dc
 28 experiments inside a Scanning Electron Microscope (SEM). By using a SEM,
 29 we achieve the resolution of the electron probe in the few-nm range, which
 30 is of great advantage as the surface roughness of the polished accelerating
 31 structures is in the same scale. It is noteworthy that this is also a unique
 32 experiment in material science due to its mesoscopic approach that bridges
 33 atomic scale (with atomic force or tunneling microscopes for example) and
 34 macroscopic (mm) optical scale. The present paper will report on instru-
 35 mental developments for SEM in-situ experiments and analysis methods to
 36 investigate the effect of a voltage breakdown on the surface.

37 **2. Instruments**

38 *2.1. Experimental setup in the ESEM*

39 A drawing of the experimental setup is shown in Figure 1. This setup is
40 installed in the vacuum chamber of a FEI XL30 Environmental SEM (ESEM)
41 equipped with a field emission gun at the Ångström laboratory at Uppsala
42 University. Measurements of field emission and breakdowns are conducted
43 mainly in this microscope. In the present work, a copper sample in the form
44 of circular disc with the diameter of 12 mm and the thickness of 2 mm is
45 fixed in a hole of a portable sample holder. The holder is set on a built-in
46 sample stage of the ESEM which has five degrees of freedom of motion: three
47 linear (x, y and z), rotation and tilt. The stage is electrically insulated from
48 the ESEM chamber. A piezoelectric linear motor Piezo LEGS Linear 10N
49 Non Magnetic Vacuum (PiezoMoter AB [7]) is mounted on a ramp attached
50 on the same holder. The ramp keeps the piezo motor linear motion in 50
51 degrees with respect to the sample holder plane in order to avoid touching the
52 objective lens of the ESEM and to be perpendicular to the sample surface.
53 A tungsten needle with a typical length of 15 mm is attached to an edge
54 of the rod of the piezo motor that is electrically insulated from the motor
55 chassis. The commercially available needle has a diameter of 500 μm with a
56 tip radius of about 500 nm. The tip can be sharpened further as is explained
57 in section 2.2. The needle can be moved close to the surface of the Cu sample
58 by the piezo motor. A PMD90 micro-stepping driver controls the motor
59 with a longitudinal positioning resolution in the several-nm range. The thin
60 needle tip permits to investigate field emissions from a localised area on the
61 surface, thus addressing point a) in the table above. Field emission currents

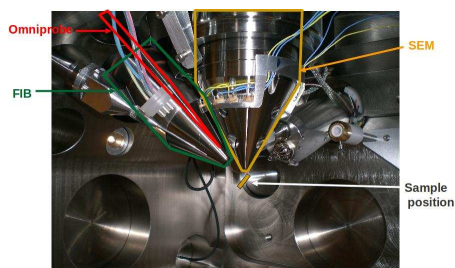


Figure 2: Inside view of the FIB: the FIB column is mounted at 52 degrees at an angle of 52 degrees with respect to the standard SEM column. The focusing distance of both beams are fixed in order to intersect at the sample surface. A W needle is mounted on the omniprobe manipulator.

62 between the needle and the sample are measured with a Keithley 6430 source-
63 meter. The background current level of the experimental setup is limited to
64 about 30 pA when the electron beam is turned on. With this low background
65 current, one can observe surface conditions of both anode and cathode before,
66 during and after experiment on site and overcome the problem b). It enables
67 us to fix the target surface condition in the sub- μm range and provides an
68 opportunity to investigate the evolution of the surface under high electrical
69 field gradient condition. The images are typically acquired by using the
70 standard secondary electron detector. A tomographic technique allows us to
71 determine the distance between the tip and the sample from SEM images:
72 As the sample setup is fixed on one holder mounted on the stage, one can
73 take images from a different point of view by tilting the stage. Images from
74 two different angles enables us to determine the gap between the anode and
75 the cathode with sub- μm accuracy, thus addressing point c) on the list.

76 *2.2. The Focused Ion Beam Microscope*

77 Considering the plasma-assisted arcing model [8, 9], it is desirable to
78 investigate the geometrical dependence of field emission on the topography
79 of the sample. Therefore, it is important to be able to modify the topography
80 of both the tip and the sample surface. A Focused Ion Beam (FIB) Dual
81 Beam device (FEI Strata DB235) is applied as an essential part to optimise
82 and understand the breakdown and tunnel-current experiments. The FIB is
83 used for 3 purposes in this work: 1) pattern the surface by ion sputtering, 2)
84 optimisation of the radius of curvature of the manipulator tip, 3) the depth
85 analysis of surface transformations of the sample under or close to break down
86 conditions. The FIB instrument consists of an ion beam column mounted at
87 an angle of 52 degrees with respect to the SEM column. The instrument is
88 also equipped with an OmniprobeTM manipulator to which the same tungsten
89 needle that is used on our custom-made manipulator can be attached. An
90 inside view of the FIB instrument is shown in Figure 2. The samples are
91 tilted by 52 degrees for patterning by the perpendicularly incident ion beam.
92 Note that images can be taken by both the SEM and the FIB immediately
93 after patterning. An example of surface patterning by creating a pillar is
94 shown in Figure 3 taken by SEM (left) and FIB (right). The size of the
95 geometrical shapes in this pattern can be defined with a precision in the
96 10 nm range.

97 The FIB can be used to vary the manipulator needle sharpness as well.
98 A needle mounted on the omniprobe manipulator can be sharpened to the
99 tip diameter of about 50 nm. Small corrugations on the sample surface can
100 therefore be precisely addressed and biased by the sharpened tip. Varying

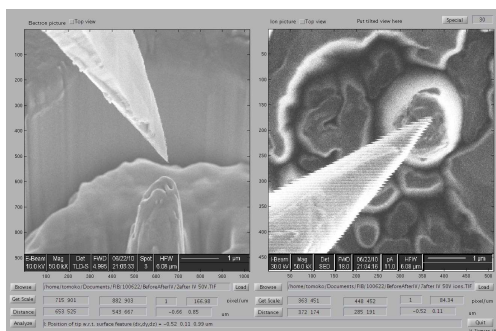


Figure 3: Capture image of the Matlab analysis program for the gap height calculation. Images of a needle and a test surface pattern are taken by SEM (left) and by FIB (right) in FIB instrument. Here the milling time is about 7 minutes for the pillar with an ion energy of 30 keV and a beam current of 3 nA. For further refinement of the pattern, lower beam currents down to 10 pA are used.

101 combinations of controlled surface pattern and needles with different radius
 102 of curvature will give us the information on the geometrical dependence of
 103 field emission.

104 As an example of the tomographic determination of the distance between
 105 the manipulator tip and the sample surface, a pair of images at different
 106 angles, here 0 and 52 degrees, is taken in Figure 3. The analysis program
 107 was developed with Matlab[®] [10] and gave a tip-sample distance of $1.0 \mu\text{m}$.
 108 The program can be used to analyse pairs of images of the sample and the tip
 109 taken at different tilt angles in the ESEM discussed in the previous section.
 110 Furthermore, surface corrugations can be analysed by this program.

111 **3. Experiments**

112 As the first step of experiment with the newly developed equipment,
113 we report in this section a demonstration of breakdown in the ESEM and
114 the depth analysis of surface transformation after the breakdown. Further
115 experiments such as tunnel current measurements still remain to be seen.
116 A breakdown experiment in the ESEM was carried out with a tungsten needle
117 and a diamond-turned copper sample. The needle was accidentally bent prior
118 to the experiment with a bi-forked tip which results to give only a rough
119 estimation of the gap about $2\ \mu\text{m}$ to the sample surface. The breakdown
occurred by putting negative voltage of more than 500 V on the needle. As

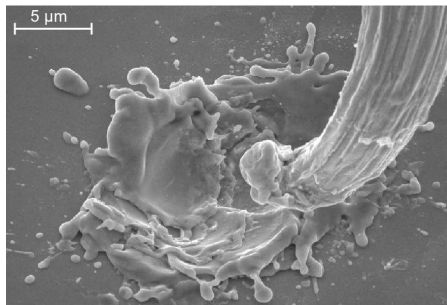


Figure 4: A SEM image of the first breakdown inside ESEM. Both cathode and anode are damaged. Note that the strong bending of the W tip was already present prior to the breakdown experiment.

120

121 shown in Figure 4, both the needle and the sample surface melted and the
122 morphology was modified. The tip is damaged up to a region where it is
123 about $2\ \mu\text{m}$ thick, whereas droplets of molten material in a size range of 0.1
124 to $1\ \mu\text{m}$ can be identified in a region of approximately $20\ \mu\text{m}$ diameter. The
125 exact place of the breakdown cannot be identified, but in view of the damage

126 caused on the sample, the place where the arc occurred was most likely not
127 more than 2 to 3 μm away from the actual tip position. Considering that
128 the sample surface is flat with a roughness in the some nanometer range, we
129 expect that the arc forms symmetrically around the original tip position. The
130 fact that the tip is not in the centre of the damage of the Cu surface could
131 be related to heating and partial melting of the W tip which, in turn, might
132 have caused an additional bending of the W tip. In order to investigate the
133 modifications of the sample structure near the surface we use FIB to sputter
134 a rectangular recess into the sample in the breakdown region. The region of
135 interest was coated with a thin film of Pt in order to protect the structures
136 caused by breakdown, using electron and ion beam induced deposition prior
137 to sputtering [11]. Observing a side of the recess with the SEM or with the
138 FIB by tilting or rotating the sample permits us to observe a cross section
139 through the sample surface [12]. In the SEM image shown in Figure 5 the
140 Pt film is visible as a surface layer. Projections of a rounded protrusion
141 with a diameter of 0.3 μm and a petal-like structure with a thickness of sub-
142 micron are shown under the Pt layer. Some white spots in the petal indicate
143 the composition of the formed feature with different materials. Layers with
144 different contrast are also shown in the thickness of about 0.3 μm from the
145 top of the flat sample surface. It might be possible to determine the energy
146 deposited on the surface during breakdown by calculating melted volume of
147 the sample by controlling the numbers of breakdown.

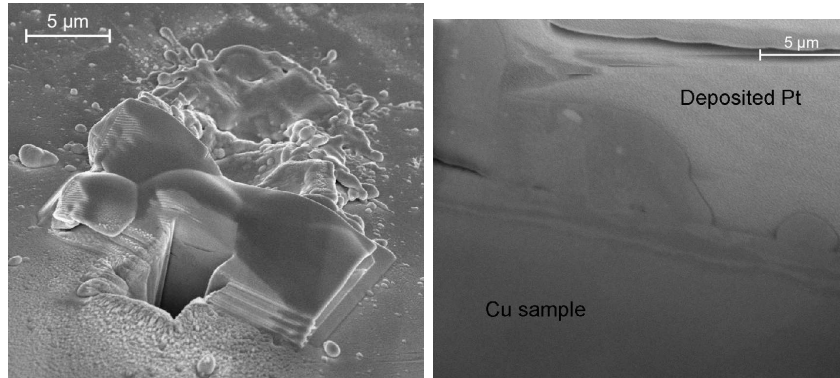


Figure 5: SEM images of breakdown area partially covered by Pt and milled by staircase patterning (top) and closeup of its cross section (bottom). Petal-like structure with thickness of submicron has clearly seen on the surface which caused by breakdown.

148 4. Conclusions and Outlook

149 In the present work we have developed an experimental setup for the
150 electrical and structural analysis of field emission and vacuum discharges
151 phenomena at the sub-micron scale. This set-up consists of a piezo con-
152 trolled in-situ nanomanipulator tip inside an SEM. We demonstrated the use
153 of a FIB for structuring of the cathode (sample) and anode (tip) surface to
154 enable field emission measurements as a function of sample topology and tip
155 radius (down to a radius of about 50 nm). The first breakdown experiments
156 were conducted in a SEM where the depth profile of the locally molten Cu
157 surface was determined by cross sectional FIB milling and subsequent SEM
158 observation. The customisable diameter of the high voltage tip as well as the
159 demonstrated modification of the topography of sample by the FIB together
160 an accuracy of the needle positioning in the several ten nanometers range
161 enable the local characterisation of breakdown phenomena. These measure-

162 ments of the dependence of field emission on surface structure in accelerator
163 materials at the sub-um scale are essential for understanding the mechanism
164 of electric discharge in high power accelerators. Such set-up makes scan-
165 ning electron microscopy and focused ion beam methods a useful tool in the
166 understanding and development of surface structures for future accelerators.

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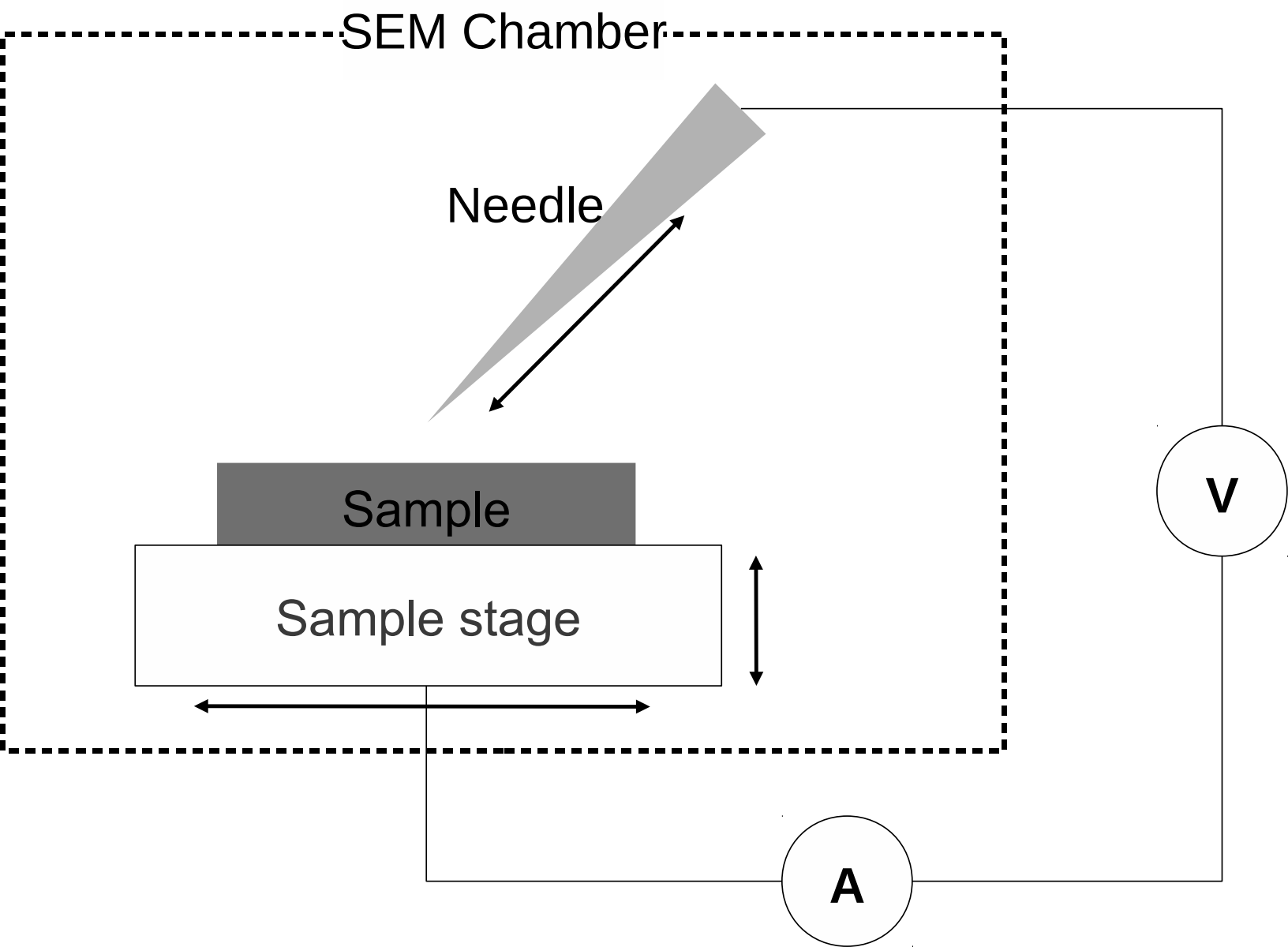
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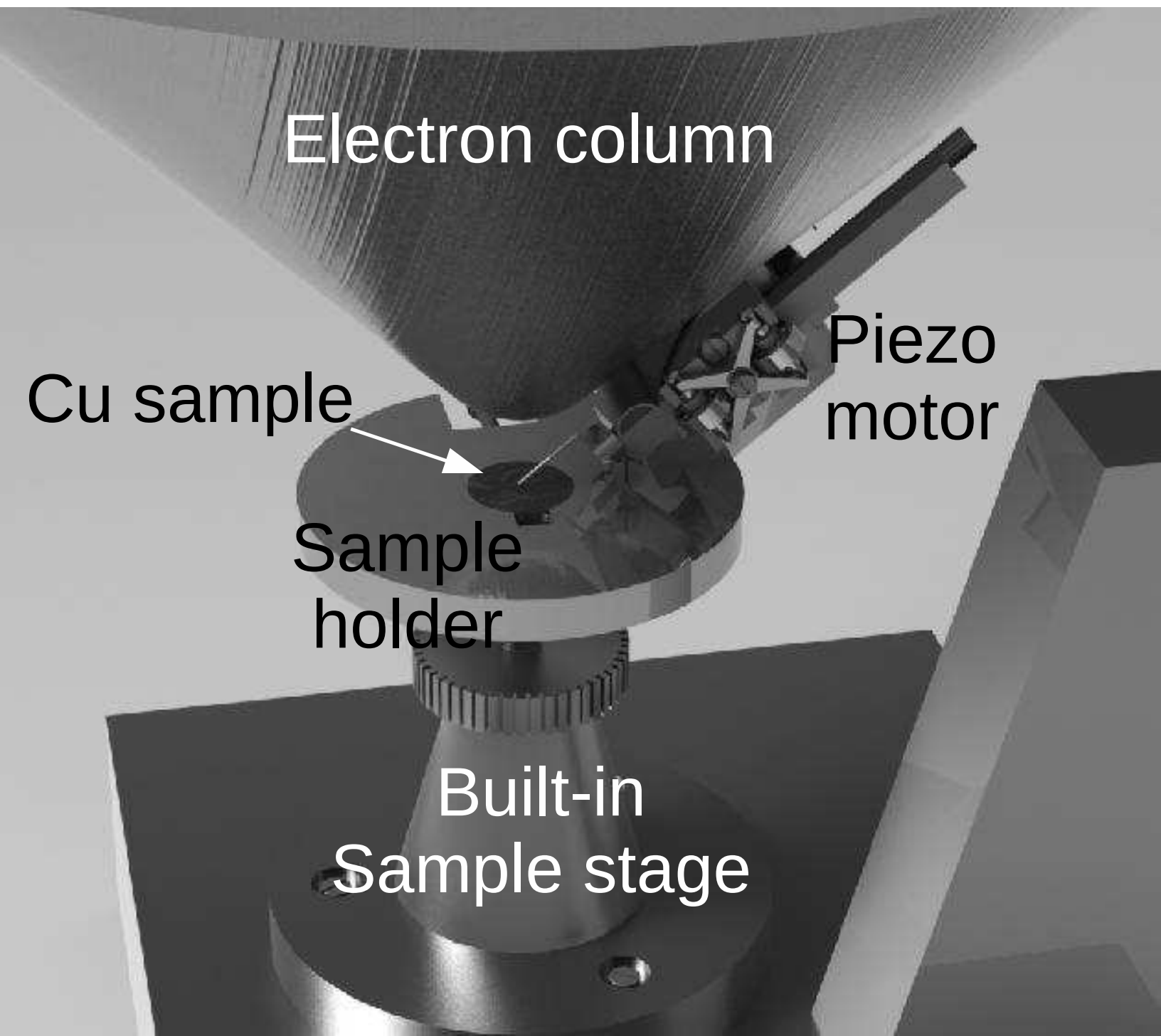
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Figure1aGrey





Electron column

Cu sample

Piezo motor

Sample holder

Built-in Sample stage